

N THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Eugene P. Marsh

Serial No.: 10/634,362

Filed: August 8, 2003

For: ATOMIC LAYER DEPOSITION OF METAL DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 S Group Art Unit: 2812

§ Examiner: Lynne Ann Gurley

Atty. Docket: 2003-0659.00/US

Confirmation No. 4954

Certificate of Mailing (37 CFR §1.8)

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to:

Commissioner for Patents, PO Box 1450, Alexandria, VA 22313-1450, on the date below://

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May 20, 2004

Date

PETITION FOR EXTENSION OF TIME UNDER 37 C.F.R. § 1.136(a)

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Applicant hereby petitions to extend the period for response to the Office Action mailed <u>January 22, 2004</u> for <u>one (1)</u> month(s), from <u>April 22, 2004</u> to <u>May 22, 2004</u>.

 \boxtimes Because May 22, 2004 falls on a Saturday in the District of Columbia, the period for response extends to May 24, 2004.

Accordingly, the requisite fee is \$ <u>110</u>. The Commissioner is requested to charge this fee, and any additional fee which may be required to Micron Technology, Inc. Deposit Account 13-3092, Order No. <u>2003-0659.00/US</u>. A duplicate copy of this petition is enclosed.

Respectfully submitted,

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110.00 DA

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